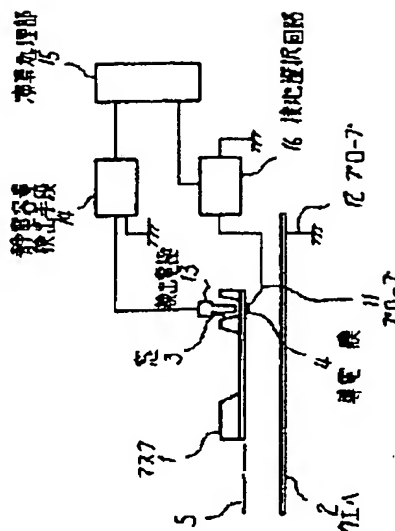


Patent Abstracts of Japan

TITLE : MEASURE OF GAP BETWEEN MASK
AND WAFER



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